

參考文獻

1. Gordon, C. G. (1991), ‘Generic criteria for vibration sensitive equipment,’ *Vibration Control in Microelectronics, Optics and Metrology, SPIE Proceedings*, Vol. 1619, pp. 71-85.
2. Bayat, A. and Gordon, C. G. (1998), ‘A discussion of vibration and noise issues in a cleanroom design: past, present, and future,’ *Proceedings of the ICCCS 14th International Symposium on Contamination Control, Institute of Environmental Sciences and Technology*, Phoenix, Arizona, pp. 139-143.
3. Amick, H. (1998), ‘On generic vibration criteria for advanced technology facilities,’ *Journal of the Institute of Environmental Science*, Vol. XL, pp. 35-44.
4. Amick, H., Gendreau, M. and Gordon, C. G. (2002), ‘Facility vibration issues for nanotechnology research,’ *Proceedings of the Symposium on Nano Device Technology*, Hsinchu, Taiwan, pp. 1-4.
5. Amick, H. and Bui, S. K. (1991), ‘A review of several methods for processing vibration data,’ *Vibration Control in Microelectronics, Optics and Metrology, SPIE Proceedings*, Vol. 1619, pp. 253-264.
6. Goucher, R. and Smith, D. (1991), ‘Vibration measurement techniques for advanced test and manufacturing facilities,’ *Vibration Control in Microelectronics, Optics and Metrology, SPIE Proceedings*, Vol. 1619, pp. 272-283.
7. Institute of Environment Sciences Contamination Control Division Recommended Practice 024.1 (1994) ‘Measuring and reporting

- vibration in microelectronics facilities IES-PR-CC024.1'
8. 周永樂 (1999) 「精密機械之振動環境研究」, 機械工業, 第 195 期, 第 163-170 頁。
 9. 王彥博、鍾立來、李建良 (2003) 「高科技廠房之微振動量測技術」, 結構工程, 第十八卷, 第四期, 第 49-74 頁。
 10. Gordon, C. G. and Tran, Y. Q. (1991), 'The influence of bases and benches on the performance of vibration-sensitive equipment,' *Vibration Control in Microelectronics, Optics and Metrology, SPIE Proceedings*, Vol. 1619, pp. 86-99.
 11. Amick, H. and Bayat, A. (1998), 'Dynamics of stiff floors for advanced technology facilities,' *Proceedings of 12th ASCE Engineering Mechanics Conference*, La Jolla, California, USA, pp.318-321.
 12. 陳俊淇、吳政三、楊金成、柯富祥 (2001) 「半導體製程黃光區的微震動來源及解決方法」, 毫微米通訊, 國家毫微米元件實驗室, 第八卷, 第三期, 第 34-38 頁。
 13. Kim, J. J. and Amick, H. (1997), 'Active vibration control in fabs,' *Semiconductor International*, Vol. 20, pp. 223-228.
 14. 王永鵬 (1998) 「淺談精密機械振動控制技術」, 機械工業, 第 184 期, 第 171-179 頁。
 15. 鍾裕亮 (1999) 「主動控制在精密機械隔振的應用」機械工業, 第 195 期, 第 171-177 頁。

- 16.Rockwood, W. B. (1992), 'Study of ground effects on building foundation vibration using two-dimensional real mode finite element analysis,' *Vibration Control in Microelectronics, Optics and Metrology, SPIE Proceedings*, Vol. 1619, pp. 228-243.
- 17.Bayat, A. and Gordon, C. G. (1994), 'An investigation of dynamic soil-structure interaction as it relates to the design of foundation system for microelectronics fabrication facilities,' *Vibration Control in Microelectronics, Optics and Metrology, SPIE Proceedings*, Vol. 2264, pp.123-134.
- 18.張亞輝 (1998) 「電子廠房之微動設計淺談」，結構工程，第十三卷，第四期，第 91-98 頁。
- 19.Huang, C. S. and Yeh, C. H. (1999), 'Some properties of randomder signatures,' *Mechanical Systems and Signal Processing*, Vol. 13, pp. 491-507.
- 20.Huang, C. S. (2001), 'Structural identification from ambient vibration measurement using the multivariate AR model,' *Journal of Sound and Vibration*, Vol. 241, pp. 337-359.
- 21.ANSI S1.1-1986 ASA 65-1986 (1993), *Specifications for Octave-Band and Factual Octave-Band Analog and Digital Filter*, Acoustical Society of America, N.Y.
- 22.Bendat, J. S. and Piersol, A. G. (2000), *Random Data- Analysis and Measurement Procedure*, 3rd edition. John Wiley & Sons, N.Y.
- 23.Brigham, E. O. (), *The Fast Fourier Transform*, Prentice-Hall, Inc., New Jersey.
- 24.Cole, H. A. Jr. (1971), 'Methods and apparatus for measuring the

- damping characteristics of a structure', *United States Patent* No.3,620,069.
- 25.Pappa, R. S. and Ibrahim, S. R. (1981), 'A parametric study of the Ibrahim time domain modal identification algorithm', *Shock and Vibration Bulletin*, Vol. 51, pp.43-72.
- 26.Loh, C. H. and Wu, T. S. (1996), 'Identification of Fei-Tsui arch dam from both ambient and seismic response data', *Soil Dynamics and Earthquake Engineering*, Vol.15, pp. 465-483.
- 27.Huang, C. S. (2001), 'Modal identification of structures from ambient vibration, free vibration, and seismic response data via a subspace approach', *Earthquake Engineering and Structural Dynamics*, Vol. 30, pp. 1857-1878.
- 28.全湘偉、邱垂鈺 (1997) 「半導體廠房製程儀具基礎暨樓版結構振動反應分析模室之建立」, 機械月刊, 第 23 卷, 第九期, 第 327~337 頁。
- 29.林義祥、姚昭智 (1999) 「微電子廠房之動力特性與振動衰減」國立成功大學建築研究所碩士論文。
- 30.黃炯憲 (1999) 「微動量測分析工具探討(二)—時間序列法」, 國家地震工程研究中心報告 NCREE-99-018。
- 31.評輝營造 (2002) 「國家毫微米實驗室新建工程設計變更方案說明 (修訂檔)」。
- 32.鄭義憲 (2003) 「國家奈米元件實驗室之微動量測與初步分析」,

國立交通大學土木工程研究所碩士論文。

33. 蕭開元、吳世全、林俊昌 (2002) 「新建工程機電系統圖說規範訂定(一)」，毫微米通訊，第九卷，第二期，第 41~48 頁。
34. 蕭開元、吳世全、林俊昌 (2002) 「新建工程機電系統圖說規範訂定(二)」，毫微米通訊，第九卷，第三期，第 45~51 頁。

